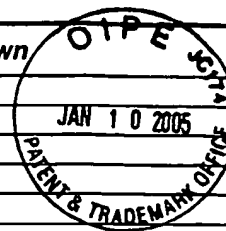


IDS Form PTO/SB/08: Substitute for form 1449A/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Application Number	10/624,593
				Filing Date	July 23, 2003
				First Named Inventor	Kei HAYASAKI
				Art Unit	4752-1756
				Examiner Name	Unknown
Sheet	1	of	1	Attorney Docket Number	04329.3100



U.S. PATENTS AND PUBLISHED U.S. PATENT APPLICATIONS					
Examiner Initials	Cite No. ¹	Document Number	Issue or Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
		US-			
		US-			
		US-			
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		US-			
		US-			

Note: Copies of the U.S. Patent Documents are not Required in IDS filed after October 21, 2004

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	Translation ⁶
		Country Code ³ Number ⁴ Kind Code ⁵ (if known)				
nm		JP 1-189123	07/28/1989	Japan		No

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Translation ⁶
		Notification of First Office Action issued by Chinese Patent Office in Chinese application No. 031503136, and English translation of Notification	Yes

Examiner Signature	<i>Priscilla Hannon</i>	Date Considered	9/20/05
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1/23/03

OMB No. 0651-0011

INFORMATION DISCLOSURE CITATION

Atty. Docket No. 04329.3100	Serial No. Not Yet Assigned 10/624,593
Applicants KeiHAYASAKI et al.	
Filing Date July 23, 2003	Group: Not Yet Assigned 1756

U.S. PATENT DOCUMENTS						
Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
ny	6,372,413 B2	04/16/02	EMA et al.	430	324	

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	Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
ny	2001-085407	03/30/01	JAPAN			ABSTRACT
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
ny	TSURUMUNE, A. et al., "Observation Device, Ultraviolet Microscope and Observation Method", Application No. 10/133,626, filed on April 29, 2002.
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Examiner <i>Nick</i>	Date Considered 9/24/05
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